

SHEET 1 OF 3

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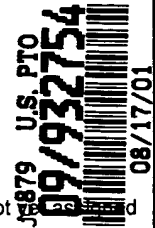
## INFORMATION DISCLOSURE STATEMENT

ATTY DOCKET NO.: QCS-001DV3

APPLICANT: KAMIENIECKI et al.

SERIAL NO.: ~~Not yet assigned~~  
09/932754

FILING DATE: August 17, 2001 GROUP: Not



## U.S. PATENT DOCUMENTS

EXAM. INIT.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
<i>g.m.H</i>	4,168,212	9/18/79	Faktor et al.			
	4,181,538	1/1/80	Narayan et al			
	4,286,215	08/28/81	Miller			
	4,333,051	06/01/82	Goodman			
	4,433,288	02/21/84	Moore			
	4,454,472	06-1984	Moore			
	4,507,334	03-1985	Goodman			
	4,544,887	10/01/85	Kamieniecki			
	4,551,674	11-1985	Miller			
	4,554,726	11/26/85	Hillenius et al.			
	4,581,578,	4/8/86	Honma et al.			
	4,599,558	7/8/86	Castellano, Jr.			
	4,663,526	05/05/87	Kamieniecki			
	4,812,756	3/14/89	Curtis et al.			
	4,827,212	05/02/89	Kamieniecki			
	4,891,584	01/02/90	Kamieniecki, et al.			
	5,025,145	06/18/91	Lagowski			
	5,087,876	02/11/92	Reiss, et al.			
	5,091,691	02/25/92	Kamieniecki, et al.			
	5,177,351	01/05/93	Lagowski			
	5,216,362	6/1/93	Verkuil			
	5,218,214	6/8/93	Tyson et al.			
	5,262,642	11/1993	Wessels et al.			
	5,453,703	9/26/95	Goldfarb			
	5,471,293	11/28/95	Lowell et al.			
✓	5,663,657	9/2/97	Lagowski et al.	✓	✓	✓

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FOREIGN PATENT DOCUMENTS									
EXAM. INIT.		DOCUMENT NUMBER	DATE	COUNTRY CODE	CLASS	SUB CLASS	FILING DATE	ABSTRACT ONLY	ENGLISH LANG Y/N
OTHER ART, JOURNAL ARTICLES, ETC.									
EXAM. INIT.	OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)								
4. H		"Extended Abstracts", Fall Meeting, October 9-14, 1983, Volume 83-2							
		"Frequency Dependence of Photo-EMF of Strongly Inverted Ge and Si MIS Structures-II. Experiments", by R.S. Nakhmanson, et al., Solid-State Electronics, 1975, Vol. 18, pp. 627-634							
		"Frequency Dependence of Photo-EMF of Strongly Inverted Ge and Si MIS Structures-I. Theory", by R.S. Nakhmanson, et al., Solid-State Electronics, 1975, Vol. 18, pp 617-626							
		"Ac Surface Photovoltages in Strongly-Inverted Oxidized p-Type Silicone Wafers", by C. Munakata, et al., Japanese Journal of Applied Physics, November, 1984, Vol. 23, No. 11, pp. 1451-1461							
		"Analysis of ac Surface Photovoltages in a Depleted Oxidized p-Type Silicon Wafer", by C. Munakata, et al., Japanese Journal of Applied Physics, June, 1986, Vol. 25, No. 6, pp. 807-812							
		"Non-Destructive Method of Observing Inhomogeneities in p-n Junctions with a Chopped Photon Beam", by C. Munakata, et al., Japanese Journal of Applied Physics, February, 1981, Vol. 20, No. 2, pp. L137-L140							
		"Determination of Surface Charge and Interface Trap Densities in Naturally Oxidized n-type Si wafers Using ac Surface Photovoltages" by H. Shimizu, et al., Japanese journal of Applied Physics, 2/1987, Vol. 26, pp. 226-230							
		"Analysis and Control of Electrically Active Contaminants by Surface Charge Analysis" by E. Kamieniecki, et al., Handbook of Semiconductor Wafer Cleaning Technology (date unknown)							
		"Non-Contact Mapping of Heavy Metal Contamination for Silicon ic Fabrication", by J. Lagowski, et al., Semicond. Sci. Technology, 1992 (month unavailable)							
		"Determination of Surface Space Charge Capacitance Using a Light Probe", by E. Kamieniecki, J. Vac. Sci. Technology, March 1982							
		"A New Method for In-Line, Real-Time Monitoring of Wafer Cleaning Operations", by E. Kamieniecki, et al., Presented During the Symposium on Ultra Cleaning Processing of Silicon Surfaces, September 9-21, 1994							
		"Surface Photovoltage Measured Capacitance: Application to Semiconductor/Electrolyte System" by E. Kamieniecki, J. Appl. Phys., November 1983							
		AN-1 Application Note - Surface Charge Profiler, "Performance Demonstration", QC Solutions, Inc., July 1994							
		An-2 Application Note - Surface Charge Profiler, "In Wafer Cleaning Monitoring", QC Solutions, Inc., September 1994							

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OTHER ART, JOURNAL ARTICLES, ETC.			
EXAM. INIT.	OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)		
4~H ↓		AN-3 Application Note - Surface Charge Profiler, "Monitoring of Wafer Cleansing Using the Surface Charge Profiler on the Back Surfaces of the Wafer", November 1994	
		"Surface Charge Profiler" brochure mailed out by QC Solutions, Inc., in January 1995	
		"Surface Charge Analysis: A New Method to . . . Oxide System", by E. Kamieniecki, Semiconductor Cleaning Technology / 1989 Electronics and Dielectrics and Insulation Divisions (month unavailable)	
EXAMINER John M. Hoyer		DATE CONSIDERED 5/5/02	

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